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Polymer Processing for Microsystems

Guest Editor:

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Deadline for manuscript submissions:

closed (1 October 2020)

Message from the Guest Editor

Dear Colleagues,

Polymers in microsystems function as basic substrates, optical devices, flow channels, gas barriers, fabrication aids, surface modifiers, mechanical protection, and so on. For a microsystem to be commercially successful, it should be mass-produced and such functions should be reliably implemented. Polymer processing allows efficient implementation of their functions and safe packaging for longer service. This Special Issue welcomes contributions on advances of the polymer processing technology for any microsystems, including electronic packages, biochips, microfluidic chips, sensors, and microsystems on large systems. Polymer processing here includes molding, printing, encapsulation, extrusion, bonding, welding, coating, and more, using any polymeric materials based on thermoplastics, thermosets, and elastomers. This Special Issue also seeks articles about new methods, applications, and reviews













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Editor-in-Chief

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